

IN THE CLAIMS:

Please amend Claims 1 to 7 as shown below.

1. (Currently Amended) A composition for forming a piezoelectric film, comprising containing a dispersoid obtained from a metallic compound, wherein the content of hafnium contained in the said composition is 3,000 ppm or less.

2. (Currently Amended) A composition for forming a piezoelectric film according to claim 1, wherein said metallic compound is ~~at least one of metallic compound~~ selected from the group consisting of organometallic alkoxides, organometallic complexes, metal organic salts salts, and metal hydroxides.

3. (Currently Amended) A composition for forming a piezoelectric film according to claim 1, wherein the content of hafnium contained in said composition is 2,000 ppm or less.

4. (Currently Amended) A method for producing a piezoelectric film comprising the steps of:

coating a substrate with a composition for forming [[a]] said piezoelectric film. to form a coating film. said composition containing a dispersoid obtained from a metallic compound, ~~in which and~~ the content of hafnium in said composition being [[is]] 3,000 ppm or less, ~~to form a coating film;~~

drying the coating film; and

sintering the dried coating film to obtain [[a)] said piezoelectric film.

5. (Currently Amended) A piezoelectric element comprising a piezoelectric film held between a lower electrode and an upper electrode, wherein the said piezoelectric film is produced by the method of claim 4.

6. (Currently Amended) A piezoelectric element according to claim 5, wherein the content of hafnium contained in said piezoelectric film held between the lower electrode and the upper electrode is 3,000 ppm or less.

7. (Currently Amended) An ink jet recording head comprising a pressure chamber communicating with an ink discharge port, a diaphragm provided in correspondence with the said pressure chamber, and the piezoelectric element of claim 5 provided in correspondence with the diaphragm, wherein an ink in the said pressure chamber is discharged through said ink discharge port by a change of volume in said pressure chamber caused by the piezoelectric element.